

**PATENT APPLICATION**

**RESPONSE UNDER 37 CFR §1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER ART UNIT 2891**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hideharu ITATANI et al.

Group Art Unit: 2891

Application No.: 10/521,248

Examiner: C. EVERHART

Filed: April 11, 2005

Docket No.: 122430

For: METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE AND SUBSTRATE  
PROCESSING APPARATUS

**AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the March 24, 2008 and April 1, 2008 Office Actions, please consider the  
following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**